IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Hwang-hee Lee et al. Serial No.: To Be Assigned Filed: Concurrently Herewith

For: METHODS OF MANUFACTURING SEMICONDUCTOR DEVICES HAVING

A RUTHENIUM LAYER USING VIA ATOMIC LAYER DEPOSITION AND

ASSOCIATED APPARATUS AND DEVICES

Date: March 16, 2004

Mail Stop PATENT APPLICATION Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

Prior to the examination of the above-referenced application, please enter the following amendments below. Applicants provide the present Preliminary Amendment pursuant to the rules stated in revised 37 C.F.R. 1.121 that became effective on July 30, 2003.

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In the Title:

Please replace the Title on page 1 of the specification with the following amended paragraph:

-- METHODS OF MANUFACTURING SEMICONDUCTOR DEVICES
HAVING A RUTHENIUM LAYER USING VIA ATOMIC LAYER DEPOSITION
AND ASSOCIATED APPARATUS AND DEVICES --.

Respectfully submitted,

D. Randal Ayers Registration No. 40,493

USPTO Customer No. 20792 Myers Bigel Sibley & Sajovec, P.A.

Post Office Box 37428

Raleigh, North Carolina 27627 Telephone: (919) 854-1400

Facsimile: (919) 854-1401

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Date of Deposit: March 16, 2004

I hereby certify that this paper or fee is being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under 37 CFR 1.10 on the date indicated above and is addressed to MAIL STOP PATENT APPLICATION, Commissioner for Patents, P.O. Box 1450, Washington, DC 20231.

Michele P. McMahan